
Artificial Neural Networks for Process Control

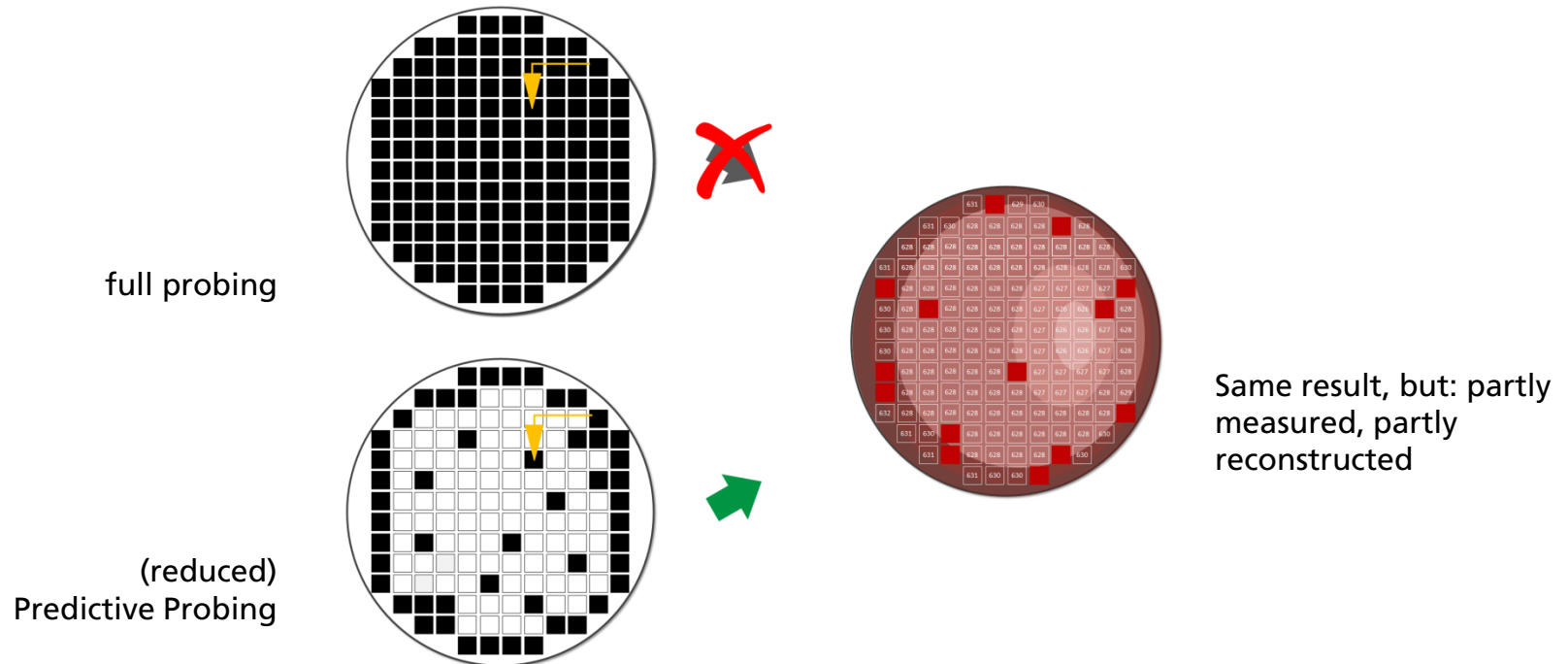
How to measure less than 10,000 chips instead of over 100,000 and still get the same result.

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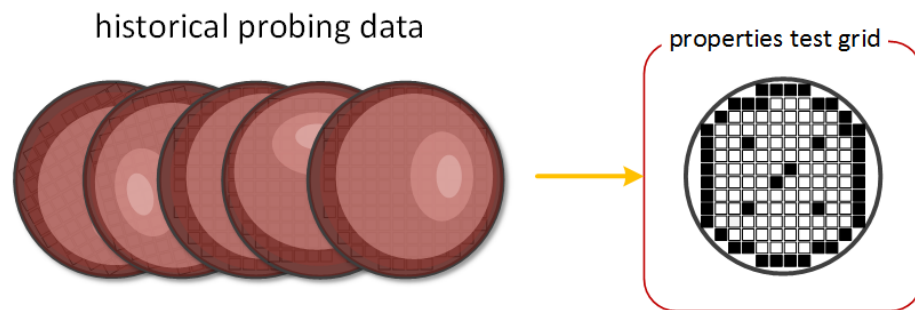
Predictive Probing

- Predictive Probing [1]
 - Reduced probing of a selected number of chips
 - Based on data analysis



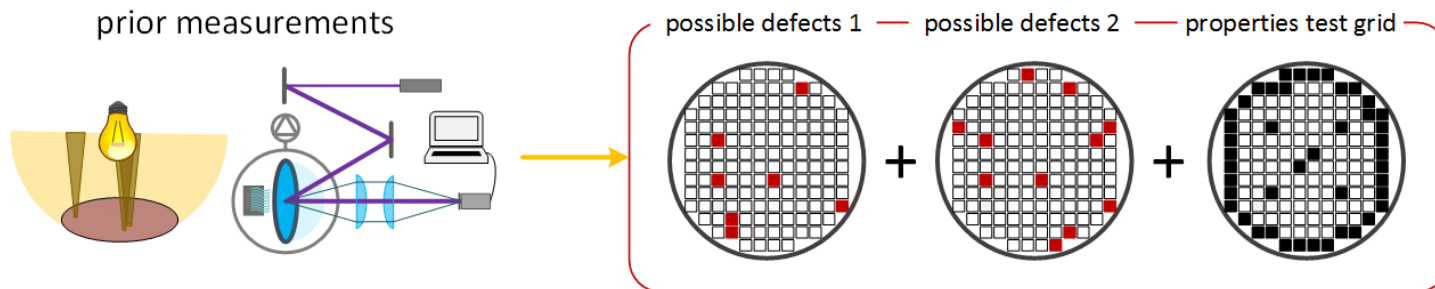
Predictive Probing | Probing Map

- Optical and electrical properties:
 - Basic test grid based on analysis of historical probing data



Predictive Probing | Probing Map

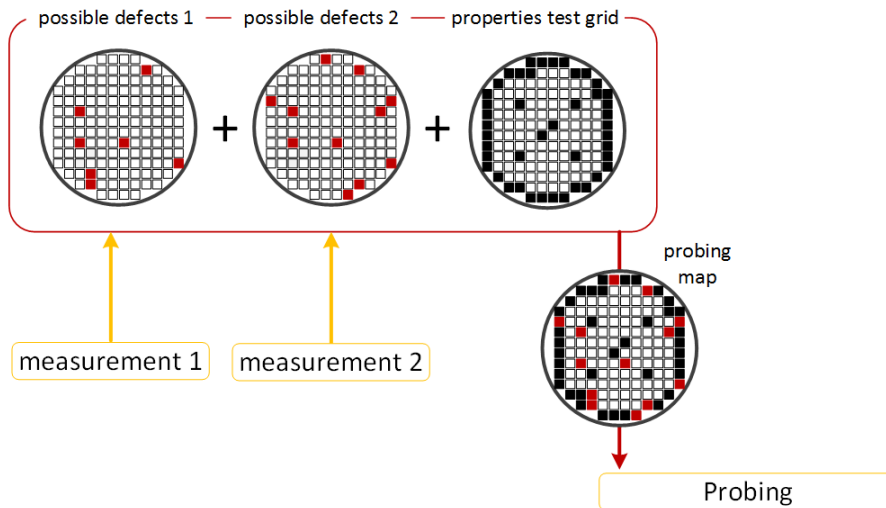
- Optical and electrical properties:
 - Basic test grid based on analysis of historical probing data
- Defects:
 - Analyse measurements prior to probing
 - Individually calculate specific defect test grid for every wafer



Predictive Probing

Two-step Predictive Probing process:

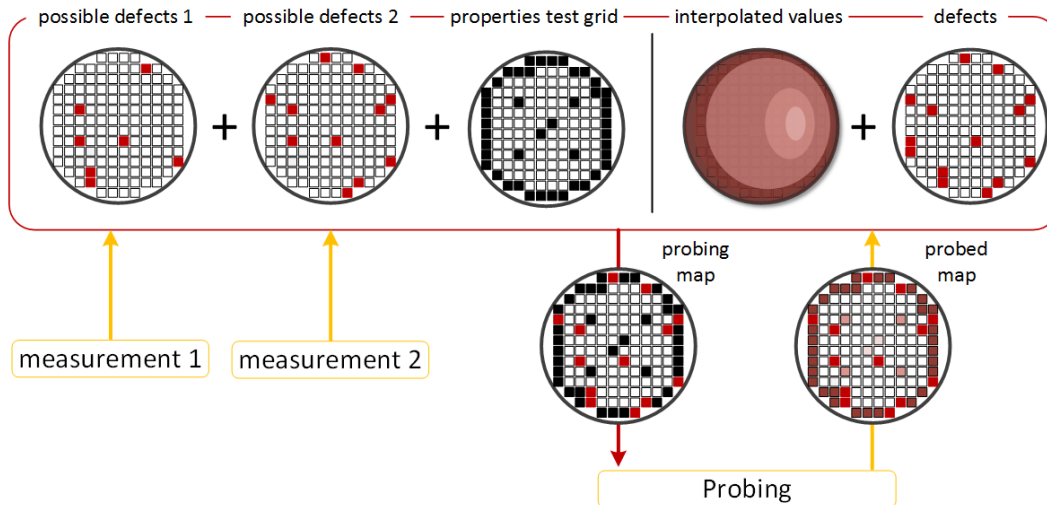
- Compile probing map to determine electrical and optical properties as well as defects and then probe selected LED-chips



Predictive Probing

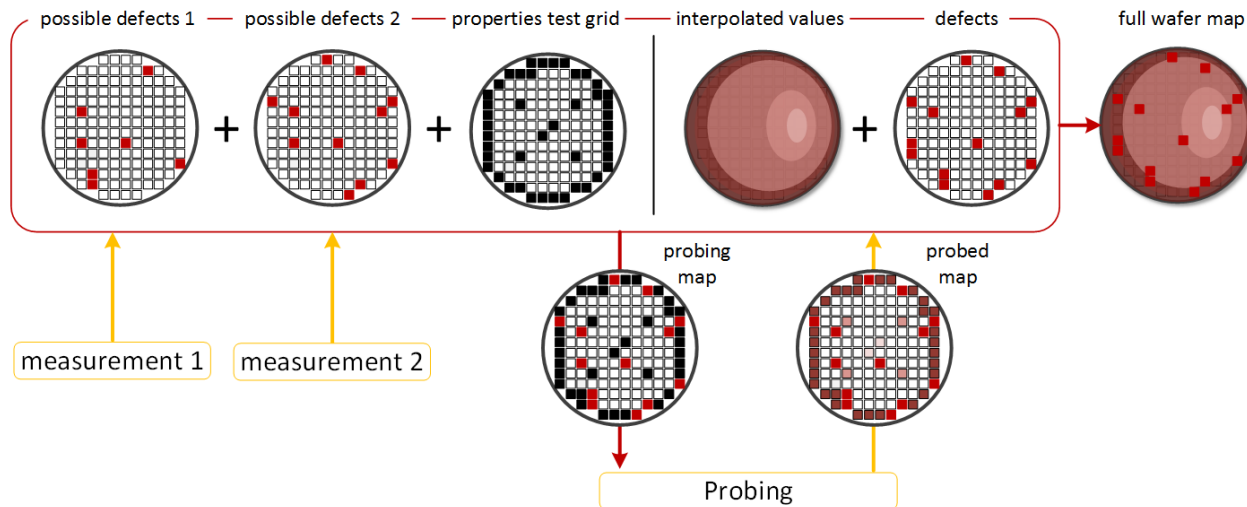
Two-step Predictive Probing process:

- Analyse prior measurements, compile probing map to determine electrical and optical properties as well as defects and probe selected LED-chips
- Read measurements, interpolate optical and electrical values and mark defect LED-chips



Predictive Probing Summary

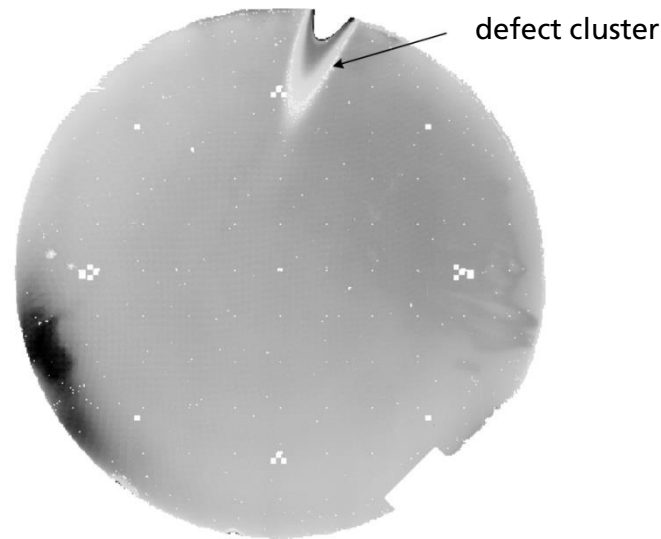
- Accurate interpolation of LED properties with < 5% measured chips
- Significant time and cost savings achieved
- Defect detection accuracy meets application requirements, almost always...



Predictive Probing | Improving defect detection

... but not for wafers with defect clusters:

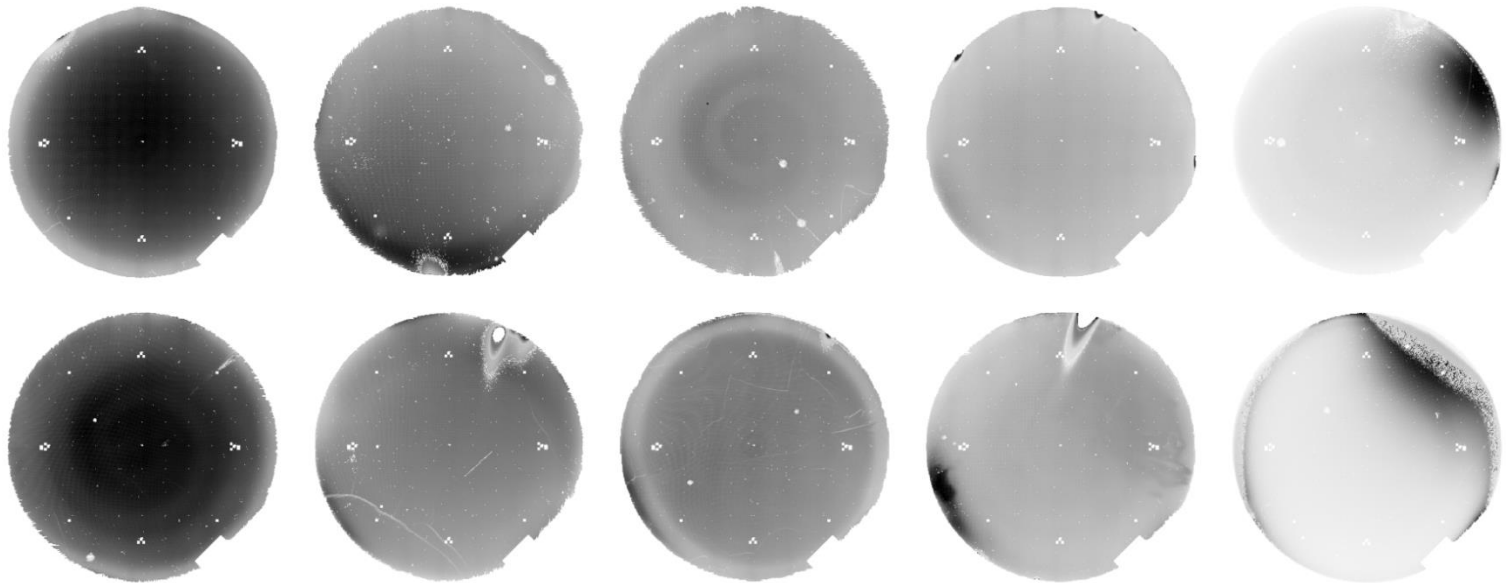
- A small percentage of wafers show defect clusters usually on the wafer edge
- No accurate detection with data analysis methods possible, only work-around solutions
- Visible for the human eye in photoluminescence measurements, though



Predictive Probing | Defect Cluster Classification

Challenges:

- Measured brightness varies highly
- So do cluster shapes and sizes
- Every single chip (>130,000) must be classified

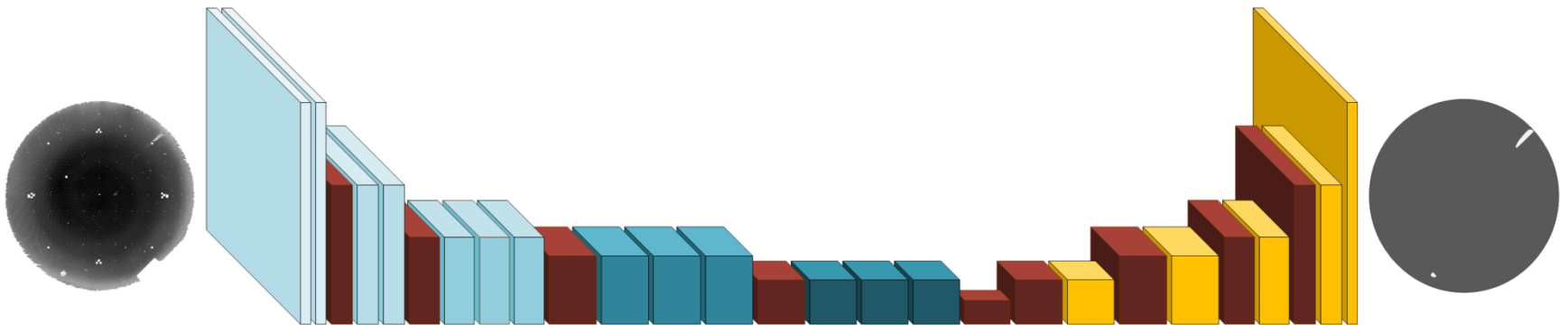


photoluminescence measurements

Defect Cluster Classification | Solution Approach

Fully Convolutional Networks [2]:

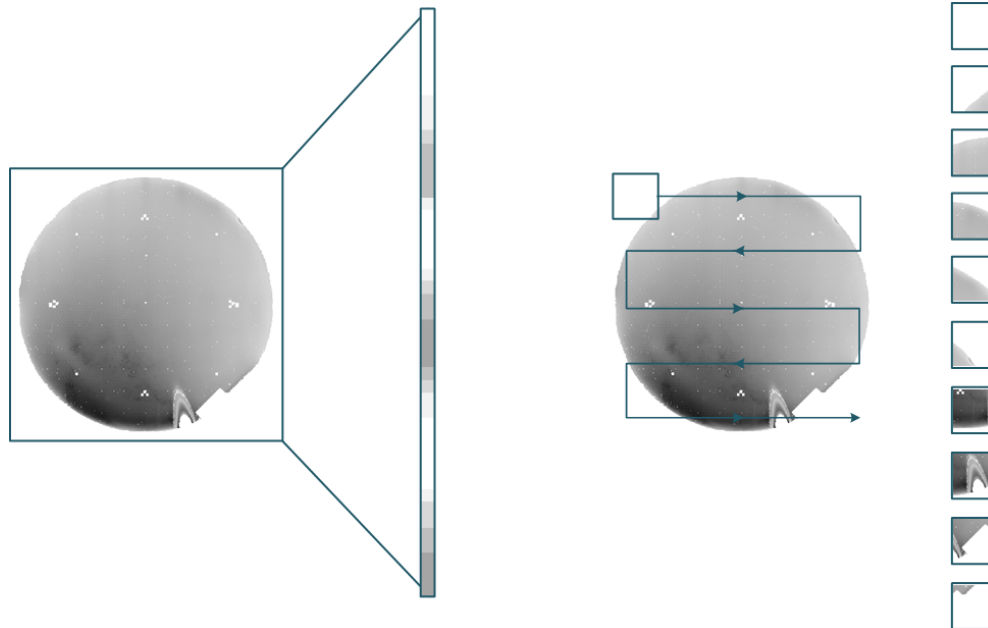
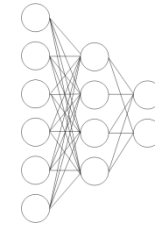
- Based on a special network architecture for computer vision
- Self-learning algorithm for pixel-wise classification



Some Intuition about Fully Convolutional Networks

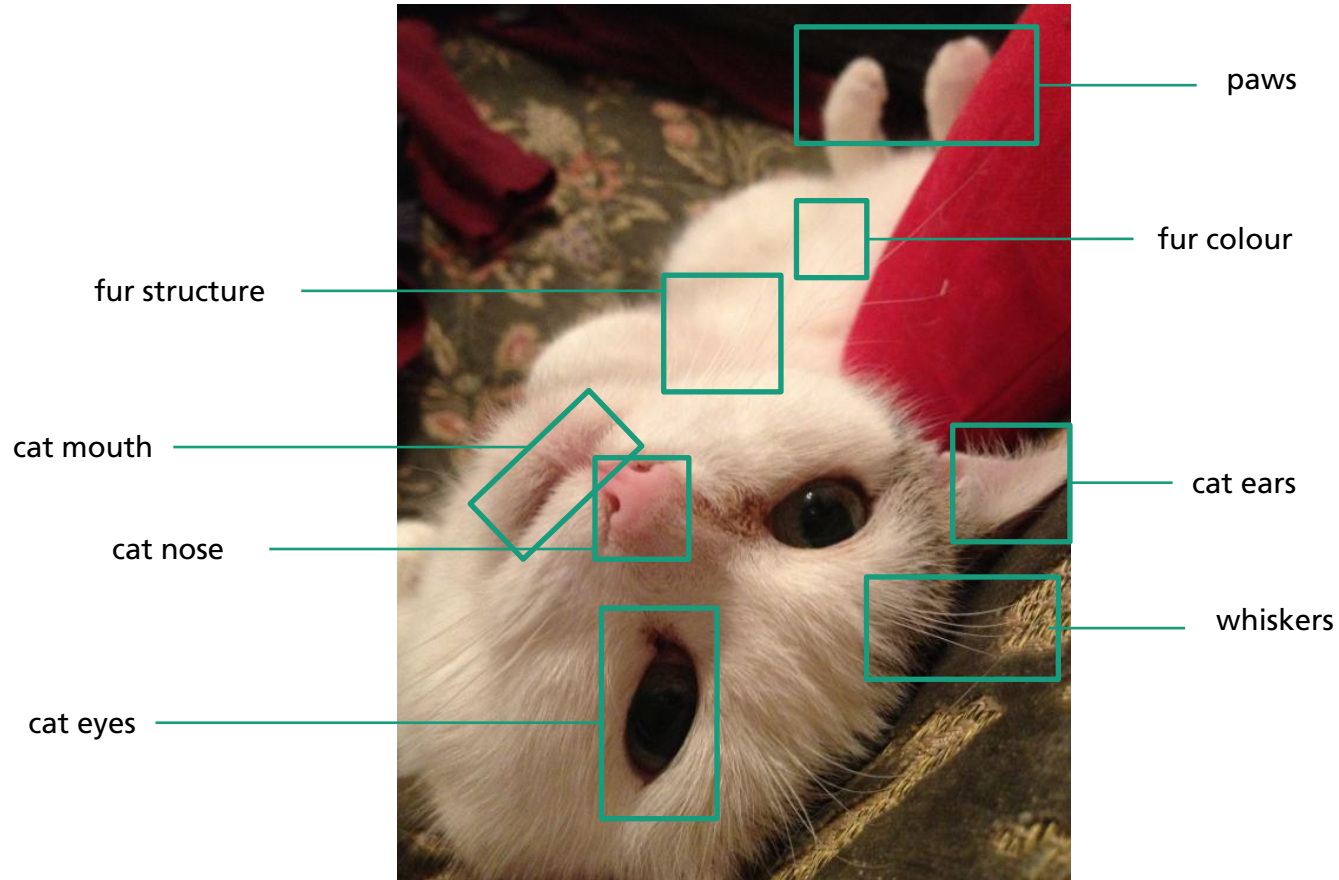
Fully Convolutional Networks:

- Vanilla (regular) neural network process vectorised data
- Computer vision networks, by contrast, preserve spatial information by filtering the image

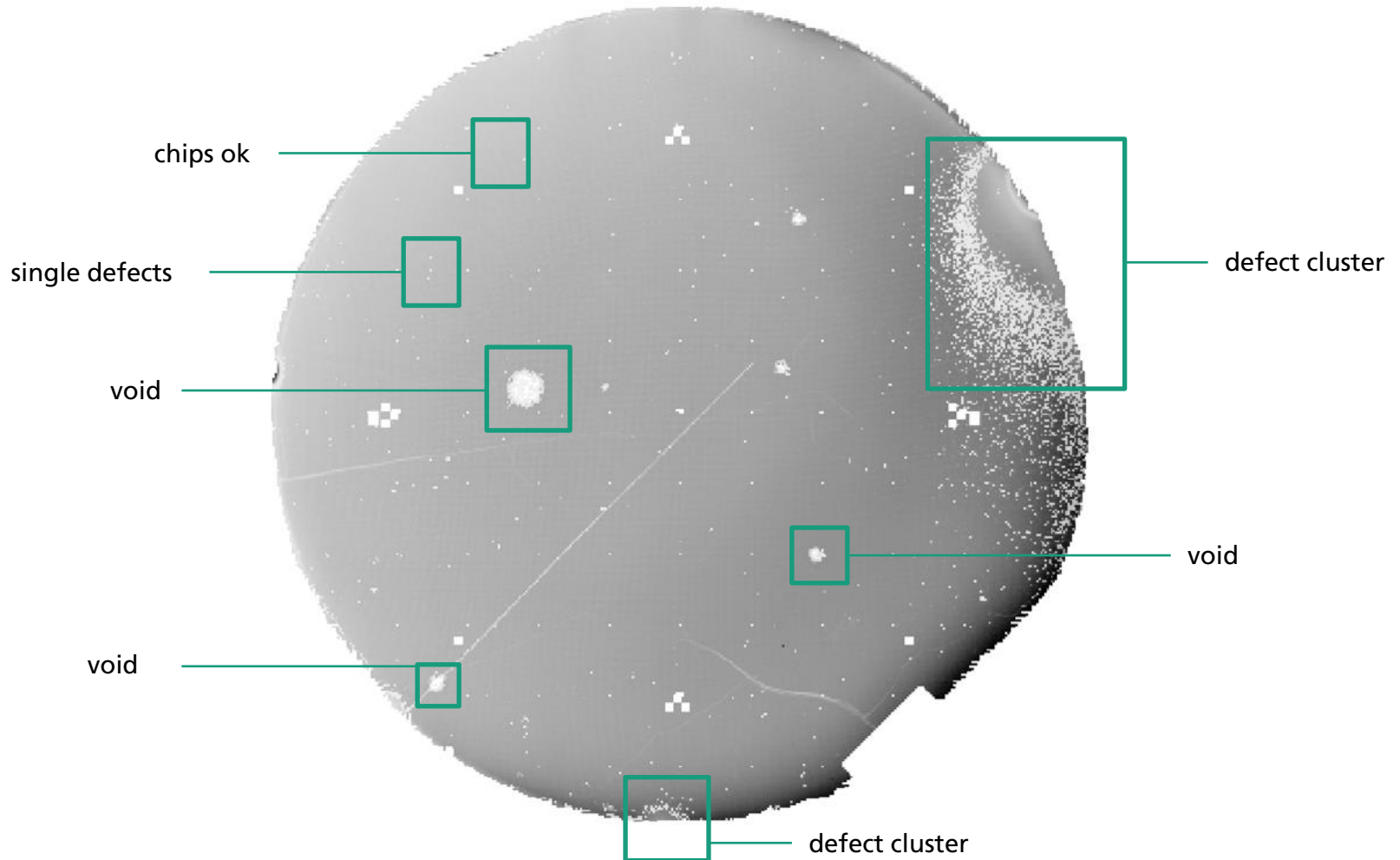


Some Intuition about Fully Convolutional Networks

Filters: feature detectors, that enable robustness against rotation, scale and translation variance

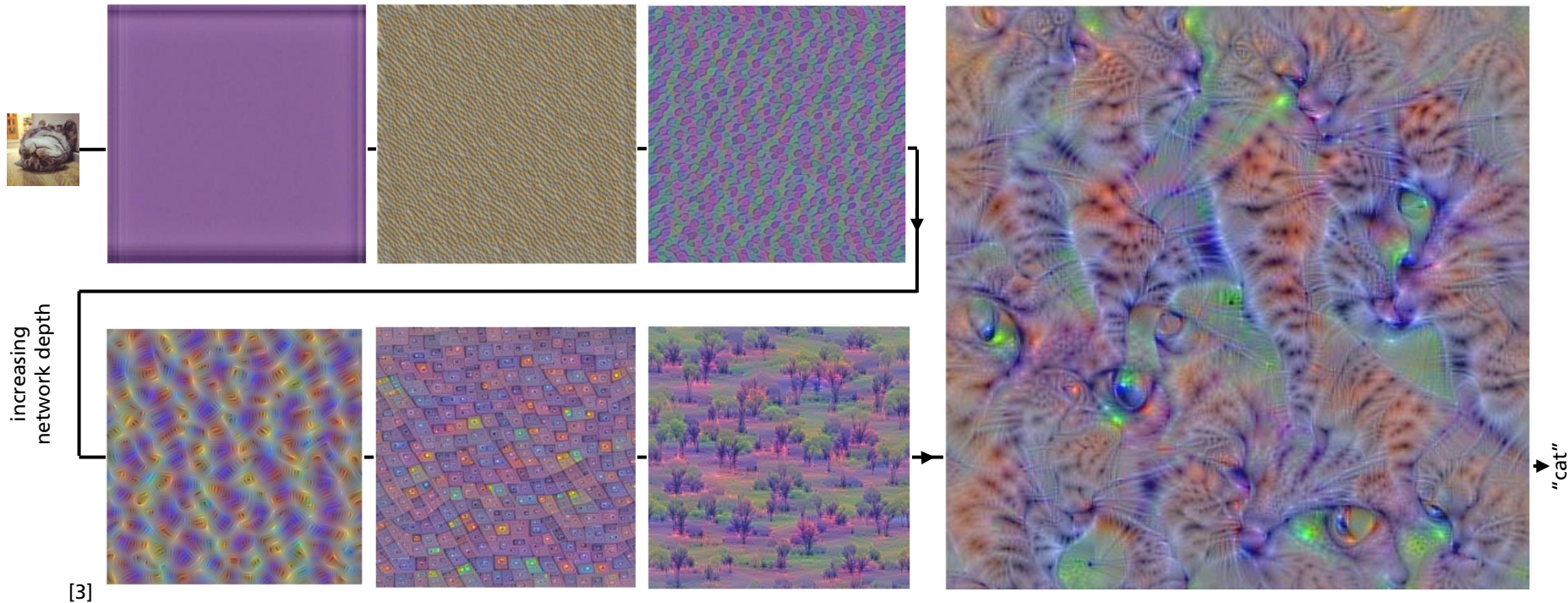


Some Intuition about Fully Convolutional Networks



Some Intuition about Fully Convolutional Networks

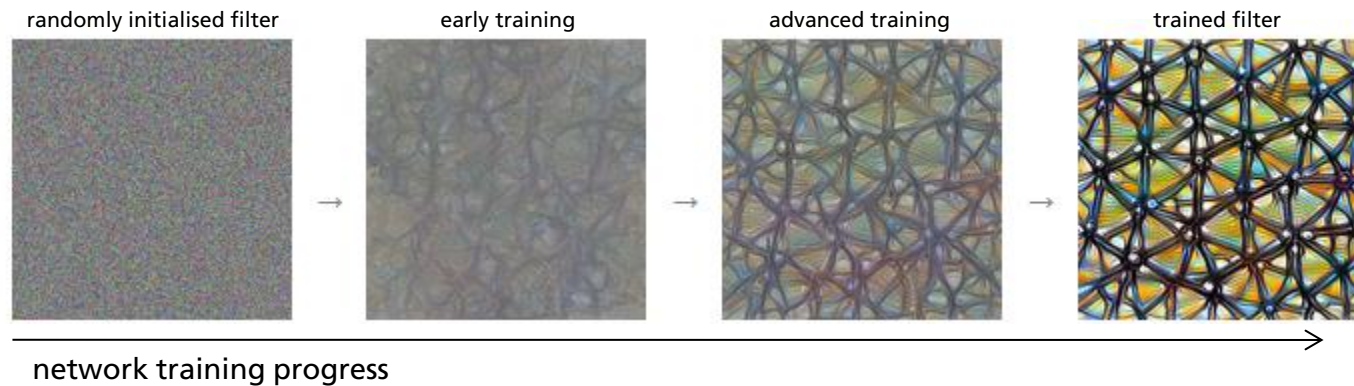
- A typical network contains thousands of filters, allowing the classification of highly variant images
- With increasing network depth filters are getting more complex



[3]

Some Intuition about Fully Convolutional Networks

- The network's performance is to learn suitable filters for the given classification task
- Therefore the network has to be trained with a carefully assembled dataset of inputs and corresponding labels



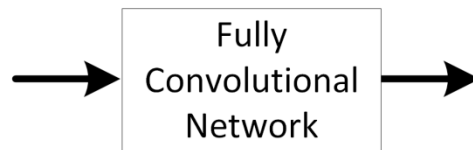
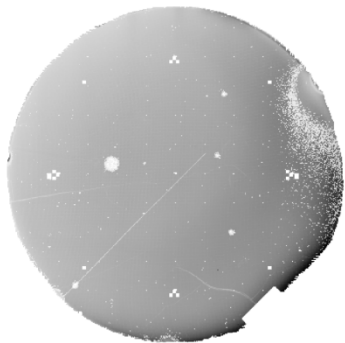
[4]

Defect Cluster Classification | FCNs

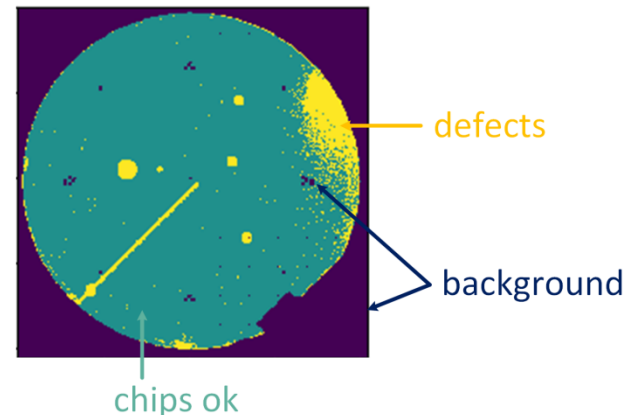
Network training:

- Input: about 100 photoluminescence measurements
- Labels: 3 prediction classes - chips ok / background / defect chips

input: photoluminescence measurement

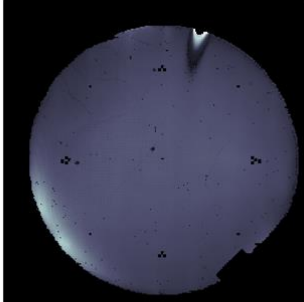


labels: class categories based on the measurement of every single chip

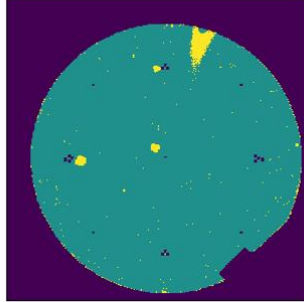


Edge Void Classification | Results

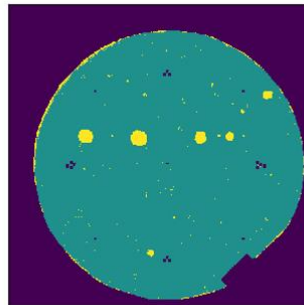
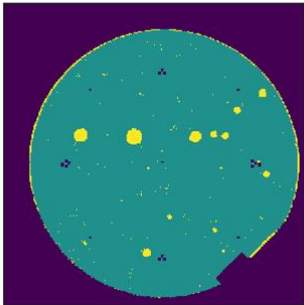
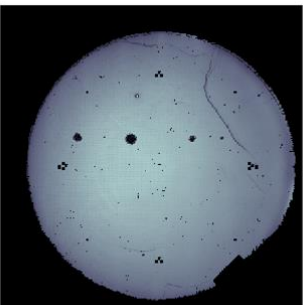
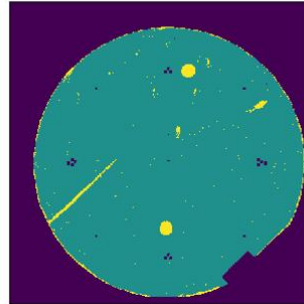
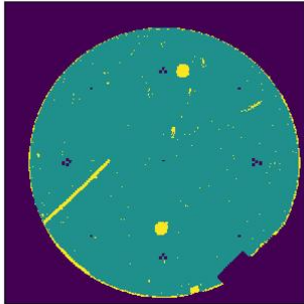
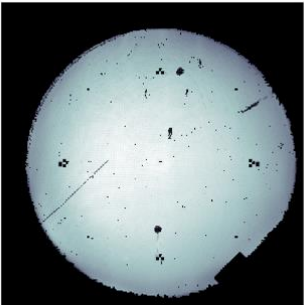
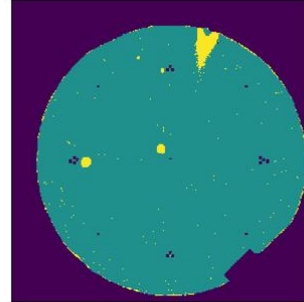
PL measurement



label (prober measurement result)



FCN prediction



Over 98.5 % of all 168,100 pixels correctly classified (test accuracy, 98.9% training accuracy)

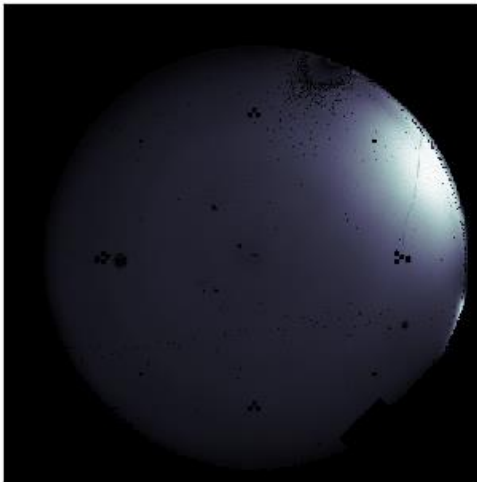
test images = not used for network training

Summary

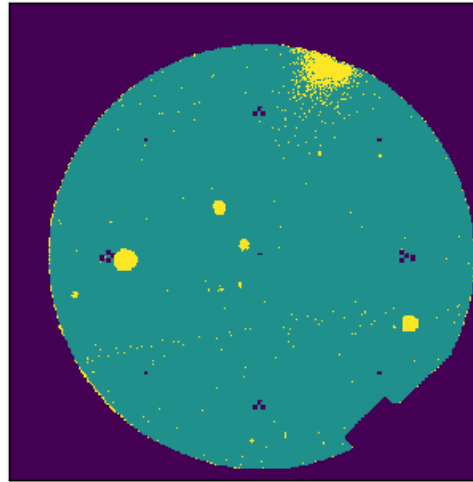
Predictive Probing supplemented with a pixel-wise defect cluster classification algorithm

- Predictive Probing defect detection accuracy significantly improved
- Deployable with every wafer / chip size
- Network knowledge transferrable to other pattern recognition tasks

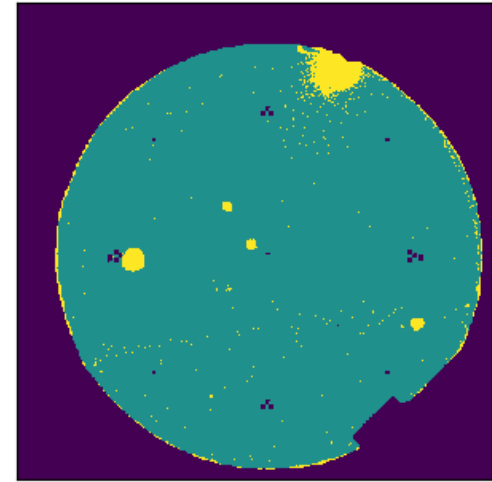
PL measurement



measurement result



network prediction

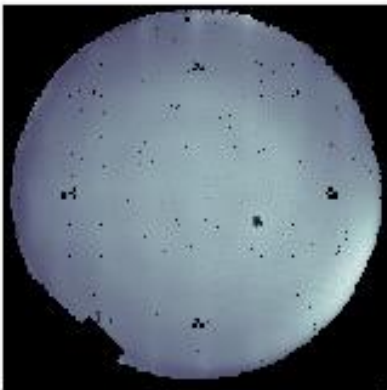


Summary & Outlook

Predictive Probing supplemented with a pixel-wise defect cluster segmentation algorithm

- Predictive Probing defect detection accuracy significantly improved
- Deployable with every wafer / chip size
- Network knowledge transferrable to other pattern recognition tasks
- Current work: object detection algorithm for process specific patterns: stripes, spirals, defect clusters, ...

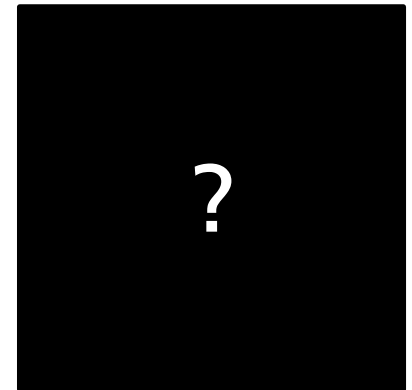
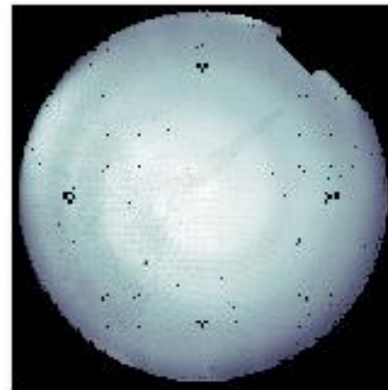
stripes



defect cluster



spiral



Thank you for your attention!

Die Arbeiten wurden durch das Bundesministerium für
Bildung und Forschung (BMBF) gefördert.



GEFÖRDERT VOM

Bundesministerium
für Bildung
und Forschung

Sources

- [1] Patent pending
- [2] Evan Shelhamer, Jonathan Long, et al.: Fully Convolutional Networks for Semantic Segmentation, 2016
- [3] <https://storage.googleapis.com/deepdream/visualz/vgg16/index.html>
- [4] <https://distill.pub/2017/feature-visualization/>